

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Eric NEYRET et al.

Confirmation No.

Application No.:

Group Art Unit:

Filing Date:

Examiner:

For: PREVENTIVE TREATMENT METHOD FOR A
MULTILAYER SEMICONDUCTOR WAFER

Atty. Docket No.: 4717-10100

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

Pursuant to applicants' duty of disclosure under 37 C.F.R. 1.56, enclosed are copies of (~~7~~) references for the Examiner's review and consideration. These references were cited in the specification of the application and in preliminary search report and a copy is enclosed.

These references are listed on the enclosed Form PTO-1449. It is respectfully requested that these references be made of record in this application by the Examiner's completion and return of the PTO Form 1449.

No fee or certification is believed to be due for this submission since the references are being submitted concurrent with the filing of this application. Should any fees be required, however, please charge such fees to **Winston & Strawn** Deposit Account No. 50-1814.

Respectfully submitted,

Date: _____

2/20/04



Allan A. Fanucci (Reg. No. 30,256)

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Enclosures

LIST OF REFERENCES CITED BY APPLICANT <i>(Use several sheets if necessary)</i>				ATTY. DOCKET NO.:		APPLICATION NO.:	
				4717-10100			
				APPLICANT:			
				Eric NEYRET et al.			
				FILING DATE:		GROUP:	
				February 20, 2004			
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA	6,150,696	11/2000		257	347	
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AI						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
							YES NO
	AJ	EP 1 158 581	11/2001	Europe			X
	AK	JP 7161948 (w/English Abstract)	6/1995	Japan			X
	AL	JP2000299451 (w/English Abstract)	10/2000	Japan			X
	AM	WO 01/15218 A1	11/2001	PCT			X
	AN	WO 03/005434 A2	1/2003	PCT			X
	AO						
OTHER REFERENCES <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>							
	AP	Jean-Pierre Colinge, "Silicon-On-Insulator Technology: Materials to VSLI", 2nd Edition" by, published by "Kluwer Academic Publishers", at pages 50 and 51."					
	AQ						
EXAMINER				DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							